

Claims:

1. (Previously Presented) A bimorph mirror presenting first and second layers of piezoelectric ceramic having opposed polarities, together with at least one electrode serving to vary at least one curvature of the mirror as a function of at least one electrical voltage applied to the piezoelectric ceramics, the mirror being characterized in that the first and second layers of piezoelectric ceramic are separated by a central core of material which forms a semirigid beam, the thickness of the central core lying in the range 1 mm to 80 mm.
2. (Previously Presented) A bimorph mirror according to claim 1, wherein the thickness of the central core lies in the range 2 mm to 80 mm.
3. (Previously Presented) A bimorph mirror according to claim 2, wherein the thickness of the central core lies in the range 5 mm to 80 mm.
4. (Previously Presented) A bimorph mirror according to claim 1, wherein said central core is constituted by a material selected from glass and silica.
5. (Previously Presented) A bimorph mirror according to claim 1, wherein the first and second layers of piezoelectric ceramic are sandwiched between two skin layers of glass or of silicon.
6. (Previously Presented) A bimorph mirror according to claim 1, wherein it presents a total thickness lying in the range 10 mm to 150 mm.
7. (Previously Presented) A bimorph mirror according to claim 1, wherein the first and second layers of piezoelectric ceramic are formed by a plurality of ceramic elements placed side by side in at least one direction along section planes, and the section planes of said second layer are offset in at least one direction relative to the section planes of said first layer.

8. (Previously Presented) A bimorph mirror according to claim 7, wherein said offset between the piezoelectric elements in at least one direction is equal to half a pitch  $P$  at which the piezoelectric elements are disposed in said direction.

9. (Previously Presented) A bimorph mirror presenting first and second layers of piezoelement ceramic having opposed polarities, together with at least one electrode enabling at least one curvature of the mirror to be caused to vary as a function of at least one electrical voltage applied to the piezoelectric ceramics, the mirror being characterized in that the first and second layers of piezoelectric ceramic are made up of respective pluralities of ceramic elements placed side by side in at least one direction along section planes, and in that the section planes of said second layer are offset in at least one direction relative to the section plane of said first layer.

10. (Previously Presented) A bimorph mirror according to claim 9, wherein said offset between the piezoelectric elements in at least one direction is equal to half a pitch  $P$  at which the piezoelectric elements are placed in said direction.